



Canon Stepper Specification **FPA-1550 MIV-W**

Reticle Size:	□5" (□126.6 mm), 0.09"t (2.3 mm t)
Wafer Size:	4" (100 mm), 5" (125 mm), 6" (150 mm)
Magnification:	X 1/5
Numerical Aperture:	0.55
Image Field :	□20 mm (∅ 28.28 mm)
Printing Wavelength:	g-line (436 nm)
Resolution:	0.6 μm
Illumination Lamp:	1 kW super-high-pressure mercury lamp
Illumination Uniformity:	≤ 1.5 %
Alignment Modes:	TTL On-Axis die-by-die alignment TTL On-Axis global alignment TTL Off-Axis global alignment
Alignment Light Source:	He-Cd laser (442 nm) He-Ne laser (633 nm)
Alignment Accuracy:	≤ 0.14 μm (mean + 3σ)
Throughput:	≥ 57 wafers / hour (6", 45 shot)
Wafer Leveling:	Die-by-die tilt Global tilt